

Form PTO-1449 U.S. DEPARTMENT OF COMMERCE (REV. 7-80) PATENT AND TRADEMARK OFFICE				Atty. Docket No. GB 010071		Serial No. 10/654366	
INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)				Applicant Pieter J. Van der ZAAG et al.			
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U.S. PATENT DOCUMENTS									
Ex. Int.		Document Number	Date	Name	Class	Sub-class	Filing Date If Approp.		
Dr	AA	5 1 3 0 8 2 9	7/14/92	Shannon	359	59	—		
Dr	AB	6461901	10/2002	Noguchi	438	150	—		
Dr	AC	6414164	7/2002	Afari - Ardakani	599	59	—		
Dr	AD	6504175	1/2003	Mei. Et al	257	66	—		
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FOREIGN PATENT DOCUMENTS									
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							Yes	No	
	AG								
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OTHER (Including Author, Title, Date, Pertinent Pages, Etc.)		
Dr	AL	"Excimer-Laser-Produced Amorphous Silicon Vertical thin Film Transistors' by A. Saitoh et al, Jpn. J. Appl. Phys. Vol. 36 (1997) pp. 668-9
Dr	AM	"IBM Technical Disclosure Bulletin, Vol. 29 No. 5, Oct 1986, pp. 2224-6
	AN	Wolf - Silicon Processes - 568 & 569. Lattice Press 1986 p 452, 462-471, 480, 501-502
Examiner		Dr
Date Considered		2/4/04

  

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.

John L Vossen Thin Film Processes II Academic Press 1991

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